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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Hiroshi MASHIMA, et al.

SERIAL NUMBER: 10/518,371

GROUP: 1715

FILED: December 28, 2004

EXAMINER: Kelly M. Gambetta

FOR: METHOD FOR PLASMA-ENHANCED CHEMICAL VAPOR DEPOSITION AND
APPARATUS FOR PLASMA-ENHANCED CHEMICAL VAPOR DEPOSITION

REQUEST TO CORRECT TITLE OF INVENTION

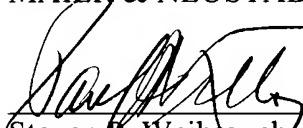
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ALEXANDRIA, VA 22313-1450

SIR:

In the matter of the above-identified application for patent, we hereby request
correction of your records to reflect the correct title of the invention. The title of the
invention should read as follows: **METHOD FOR PLASMA-ENHANCED CHEMICAL
VAPOR DEPOSITION AND APPARATUS FOR PLASMA-ENHANCED CHEMICAL
VAPOR DEPOSITION.**

Respectfully Submitted,

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